



UPPSALA
UNIVERSITET

Order form ion implantations

* = optional, or filled in by operator

Ordered byTelephone

Account No.*

Implantation date*

Ion

Tilt angle

Target heating

Batch No.*

General comments*

.....

<i>Wafer No.</i>	<i>Target position*</i>	<i>Energy (keV)</i>	<i>Dose (cm⁻²)</i>	<i>Comments*</i>

Operator*